

### Abstract of the Disclosure

According to the ferroelectric device of the present invention, the crystalline structure in the ferroelectric film is improved and the physical characteristics of the ferroelectric device can improve .

A method for manufacturing a ferroelectric device according to the present invention comprises a step for: forming successively a contact film, a lower electrode, a ferroelectric film and an upper electrode on an insulating film; performing an etching to the upper electrode and the ferroelectric film; and heat-treatment the ferroelectric film under a condition of covering the contact film with the lower electrode.